Special Issue

Micromachined Gas Sensors

Message from the Guest Editor

Advanced micromachining techniques create opportunities for the development of revolutionary new gas sensors that are small enough for integration into microelectronic systems and instrumentation, more easily deployable in a multitude of sensing applications, and capable of sensing unique aspects of the environment more accurately, safely, and reliably than ever before. This Special Issue is dedicated to showcase research papers, short communication, and review articles that focus on micromachined gas sensors theoretical foundations, advanced design and use of sensors and sensor arrays, micromachined sensor technologies toward early detection. micromachining and sensor optimization, sensor analytical modeling and design simulations, sensing and structural material selections, practical industrial, environmental and healthcare applications, sensor evaluations and characterizations methods, and advanced micromachined gas sensor fabrication process.

Guest Editor

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You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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